

# LAMP2013 Program

DAY-1: July 23 (Tue)		DAY-2: July 24 (Wed)				DAY-3: July 25 (Thu)				DAY-4: July 26 (Fri)				
8:30														8:30
9:00		<b>ROOM 1</b> Session 9 LPM SP1-1: Laser Synthesis of Nano- Materials (8:30-10:00)	<b>ROOM 2</b> Session 12 LPM Ultrafast Laser - Beam Shaping - (8:30-9:50)	<b>ROOM 3</b> Session 15 LPM Micro-welding (8:30-9:50)	<b>ROOM 4</b> Session 18 HPL 3 Welding I (8:30-9:50)	<b>ROOM 1</b> Session 21 LPM Glass Processing II (8:30-10:00)	<b>ROOM 2</b> Session 25 LPM Beam Delivery Architectures and Optical Systems for Micro Processing (8:10-10:00)	<b>ROOM 3</b> Session 29 LPM Nano Fabrication (8:30-9:50)	<b>ROOM 4</b> Session 33 HPL 6 Welding IV (8:30-10:00)	<b>ROOM 1</b> Session 36 LPM Ultrashort Pulsed Laser Processing toward Industrial Application I (8:30-10:10)	<b>ROOM 2</b> Session 38 LPM Surface Modification I (8:40-10:00)	<b>ROOM 3</b> Session 40 LPM VUV and UV Lasers (8:50-10:00)	<b>ROOM 4</b> Session 42 HPL 9 Surface Treatment II (8:40-10:00)	9:00
9:30														9:30
10:00	<b>ROOM 1</b> <b>OPENING REMARK</b> (9:50-10:00)  <b>PLENARY SESSION</b> (10:00-12:00)	<b>COFFEE BREAK</b>				<b>COFFEE BREAK</b>				<b>COFFEE BREAK</b>				10:00
10:30		<b>ROOM 1</b> <b>SHORT PRESENTATION</b> for <b>POSTER SESSION I and II</b> (10:30-12:00)				<b>ROOM 22</b> Session 22 LPM 3D Fabrication I (10:20-12:00)	<b>ROOM 26</b> Session 26 LPM Ultrafast Laser - Surface Structuring - (10:20-12:00)	<b>ROOM 30</b> Session 30 LPM Advanced Micro and Nano Processing (10:20-12:00)	<b>ROOM 4</b> Session 34 HPL 7 Welding V (10:30-12:00)	<b>ROOM 1</b> Session 37 LPM SP3-2: Ultrashort Pulsed Laser Processing toward Industrial Application II (10:30-12:00)	<b>ROOM 2</b> Session 39 LPM Surface Modification II (10:30-11:50)	<b>ROOM 3</b> Session 41 LPM VUV and UV Laser Applications (10:30-11:50)	<b>ROOM 4</b> Session 43 HPL 10 Cutting and Drilling (10:30-11:50)	10:30
11:00		<b>POSTER SESSION I &amp; EXHIBITION LUNCH TIME</b> (Main Hall A) (12:00-13:50)				<b>POSTER SESSION II &amp; EXHIBITION LUNCH TIME</b> (Main Hall A) (12:00-13:50)				<b>LUNCH TIME</b>				11:00
11:30														11:30
12:00	<b>LUNCH TIME</b>				<b>POSTER SESSION I &amp; EXHIBITION LUNCH TIME</b> (Main Hall A) (12:00-13:50)				<b>POSTER SESSION II &amp; EXHIBITION LUNCH TIME</b> (Main Hall A) (12:00-13:50)				12:00	
12:30														12:30
13:00														13:00
13:30														13:30
14:00	<b>ROOM 1</b> Session 1 LPM Patterning I (14:00-15:40)	<b>ROOM 2</b> Session 3 LPM SP L2-1 High Speed Imaging and Time Resolved Measurements I (14:00-15:30)	<b>ROOM 3</b> Session 5 LPM Glass Processing I (14:00-15:40)	<b>ROOM 4</b> Session 7 HPL 1 System I (14:00-15:40)	<b>ROOM 1</b> Session 10 LPM SP1-2 Laser Nano- structuring (14:00-15:30)	<b>ROOM 2</b> Session 13 LPM Ultrafast Laser - Surface Modification - (14:00-15:40)	<b>ROOM 3</b> Session 16 LPM Film Deposition/ PLD (14:00-15:50)	<b>ROOM 4</b> Session 19 HPL 4 Welding II (14:00-15:40)	<b>ROOM 1</b> Session 23 LPM 3D Fabrication II (14:00-15:40)	<b>ROOM 2</b> Session 27 LPM Ultrafast Laser - Nano- technology - (14:00-15:40)	<b>ROOM 3</b> Session 31 LPM Bio Applications (14:00-15:40)	<b>ROOM 4</b> Session 35 HPL 8 Surface Treatment I (14:00-15:30)	<b>ROOM 1</b> Session 44  <b>LPM/HPL Joint Session: Advanced Laser Processing</b>  (13:30-15:40)	14:00
14:30														14:30
15:00														15:00
15:30	<b>COFFEE BREAK</b>				<b>COFFEE BREAK</b>				<b>COFFEE BREAK</b>				15:30	
16:00	<b>ROOM 1</b> Session 2 LPM Patterning II (16:00-17:50)	<b>ROOM 2</b> Session 4 LPM SP L2-2 High Speed Imaging and Time Resolved Measurements II (16:00-17:40)	<b>ROOM 3</b> Session 6 LPM Direct Write/LIFT (16:00-18:00)	<b>ROOM 4</b> Session 8 HPL 2 System II (16:00-17:50)	<b>ROOM 1</b> Session 11 LPM SP1-3 Laser Nano- fabrication (16:10-18:00)	<b>ROOM 2</b> Session 14 LPM Ultrafast Laser - Glass Processing - (16:10-18:10)	<b>ROOM 3</b> Session 17 LPM Fundamental Aspects (16:10-18:10)	<b>ROOM 4</b> Session 20 HPL 5 Welding III (16:10-18:10)	<b>ROOM 1</b> Session 24 Joint Special Session: Tailored Surfaces by Laser Additive Manufacturing (16:00-18:00)	<b>ROOM 2</b> Session 28 LPM Ultrafast Laser - Abration - (16:00-18:20)	<b>ROOM 3</b> Session 32 LPM Nano- particle (16:00-18:00)	<b>Outstanding Awards (15:40-) Closing Remark (-16:00)</b>		16:00
16:30														16:30
17:00														17:00
17:30														17:30
18:00														18:00
18:30					<b>To Banquet</b> (on foot from the venue, 18:30-)									18:30
19:00					<b>BANQUET (19:00-21:00)</b> Hotel Nikko Niigata, 4F, Room "Toki-no-ma"									19:00
21:00														21:00